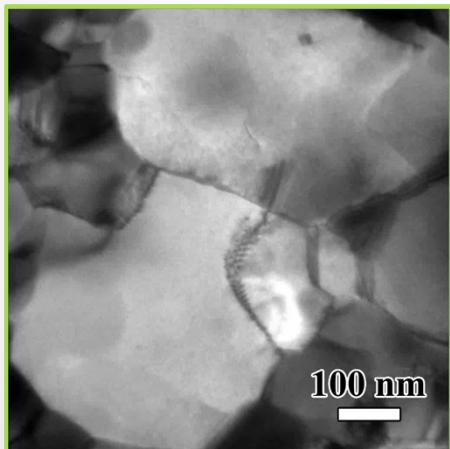


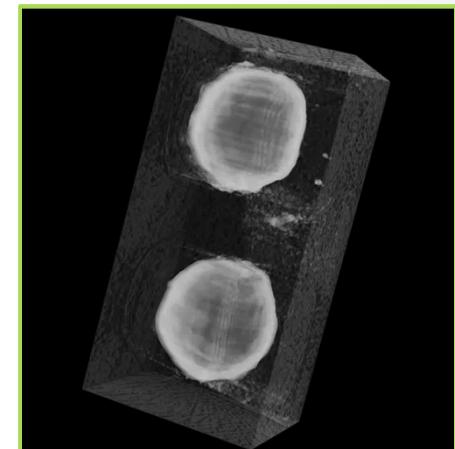
# Ion Beam Modification of Sliding Electrical Contacts and Nanomaterials



• • •

## Nanoscale Observations to Implementation

10 April, 2015



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# Motivation



- Sliding electrical contacts demand:
  - good conductivity
  - chemical stability
  - wear resistance
- Au meets the conductivity and chemical stability demands, but it lacks wear resistance.

## 1. Ion beams can modify electrical and mechanical properties.

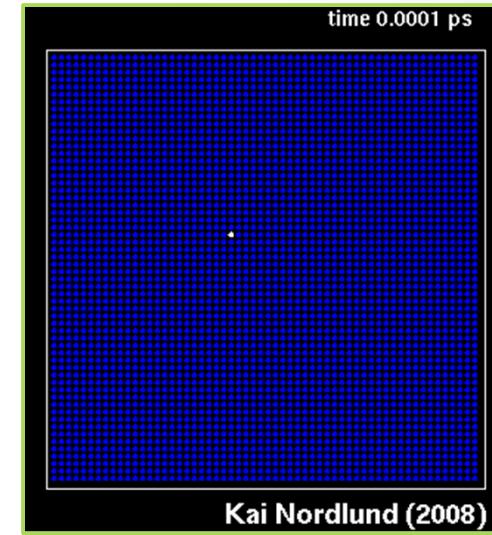
- Nanoparticle shape and size influences optical properties

## 2. Ion beams can modify nanoparticles on the nanoscale.

# Ion Beam Modification



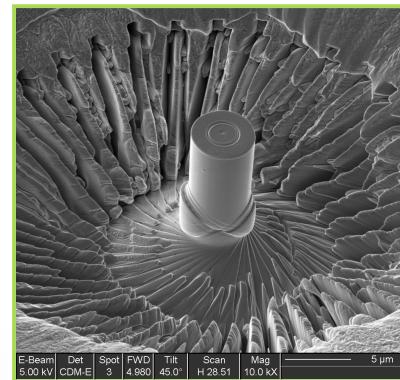
- Energetic ion displaces one or more target atoms
  - Frenkel (vacancy-interstitial) pair
  - Collision cascade
  - Electronic interactions
- Ability to alter microstructure
  - Local reorganization of atoms
  - Defect production
  - Implanted species



via Wikimedia Commons.

• **Interactions depend strongly on ion mass + energy and target atom mass + bonding.**

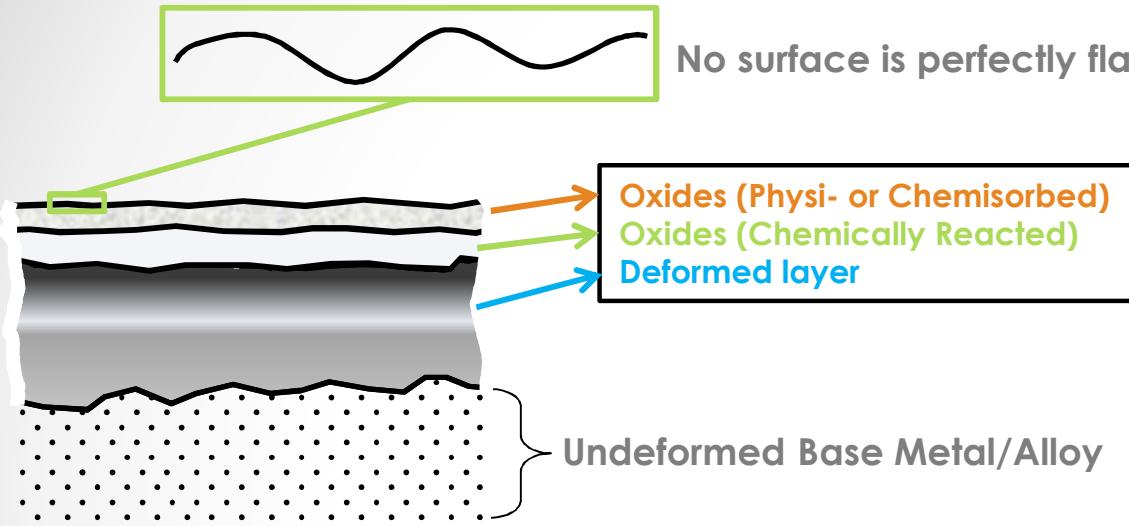
- Ions beams may be used for...
  - Semiconductor doping
  - Material removal (FIB milling)
  - Patterning/lithography
  - Analysis (mass spectrometry, ion microscopy)



Averback, J Nucl Mater, 1994.  
Ghaly & Averback, Phys Rev Lett, 1994.  
Nordlund & Djurabekova, J Comput Electron, 2014.



# Nature of Metallic Surfaces



No surface is perfectly flat.

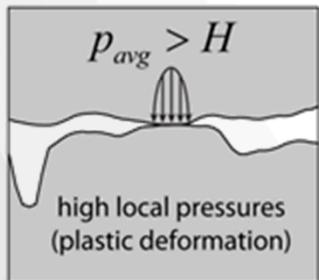
Oxides (Physi- or Chemisorbed)  
Oxides (Chemically Reacted)  
Deformed layer

Real area of contact ( $A_r$ ) to be minimized for low adhesion (Low Adhesive Wear)...

...or maximized for low electrical contact resistance (ECR).

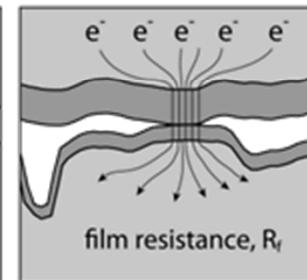
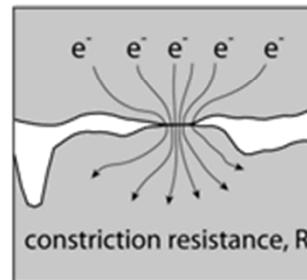
## Asperity Contacts, Constriction, Asperity Contacts and Surface Films

areal sum of asperity contacts and surface films define electrical contact resistance



... for metal contacts the real area is a function of hardness and contact force (Bowden & Tabor, 1939):

$$A_r \cong \frac{F_n}{H}$$



... ECR is a function of the constriction and film resistances:

$$ECR = \sum_i (R_{c,i} + R_{f,i})$$

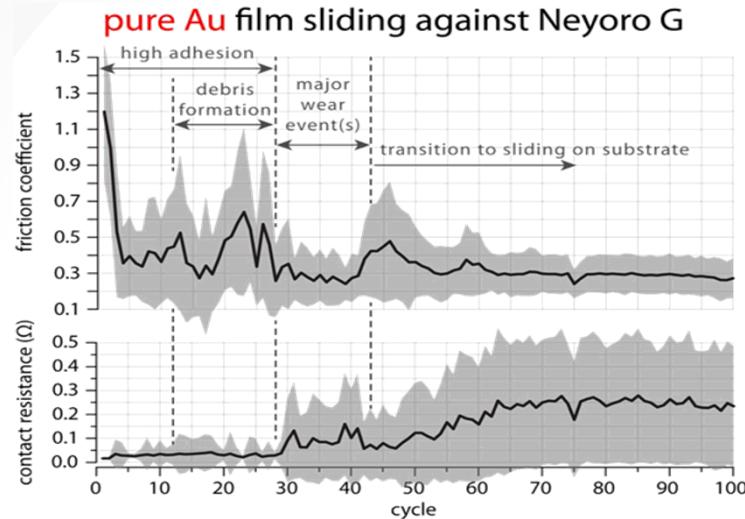
Archard, Journal of Applied Physics (1953) 24:981

R. Holm, Electrical Contacts Handbook (1958) Berlin: Springer-Verlag

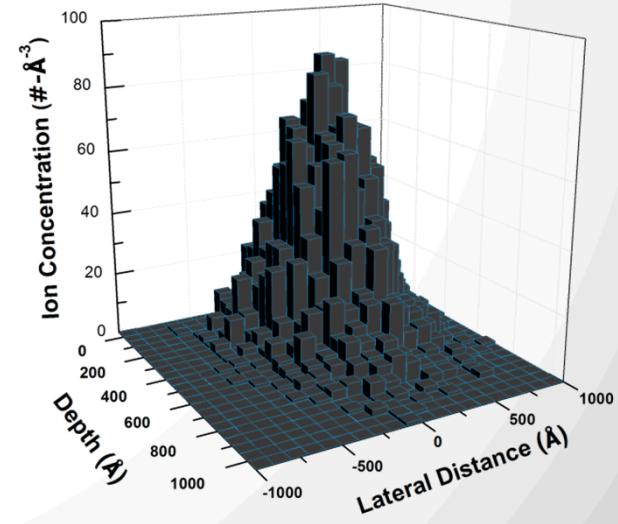
Greenwood & Williamson, Proc. Royal Society (1966) A295:300

T.W. Scharf & S.V. Prasad, Journal of Material Science (2013) 48:511-531

# Experimental and Modeling Approaches

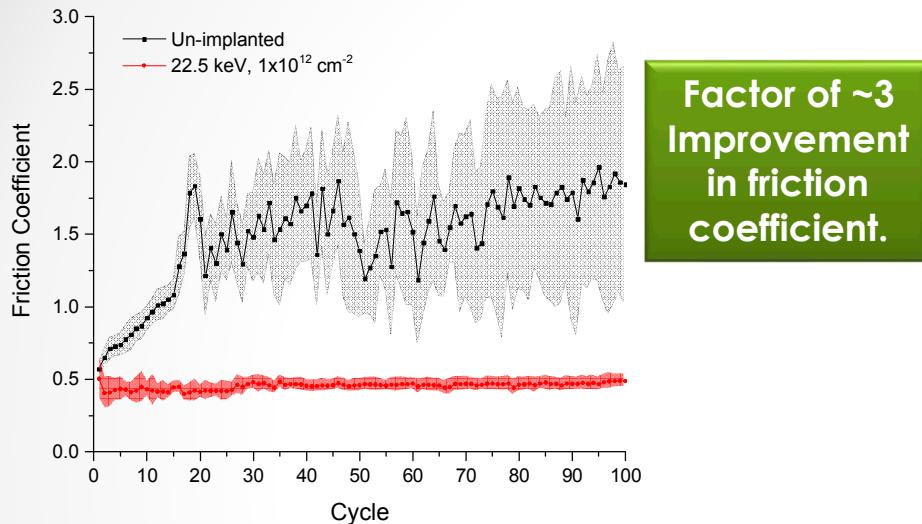


- **Simulations:** SRIM 2008 (The Stopping and Range of Ions in Matter, J.F. Ziegler, M.D. Ziegler and J.P. Biersack)
  - Monte-Carlo simulation of kinematic interaction based on empirical data fitted functions
  - Input variables of target material include density, AMU, and thickness.
  - Input variables of ions include AMU, energy, and angle of incidence.
  - Assumes isotropic material, thus no consideration for channeling effects

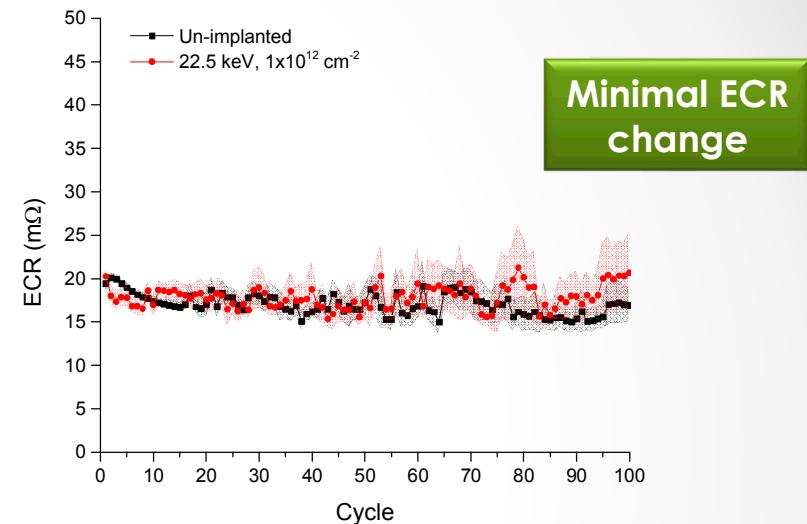


# ECR and Wear Measurements

Au implanted @ 22.5 keV to  $1 \times 10^{12} \text{ cm}^{-2}$

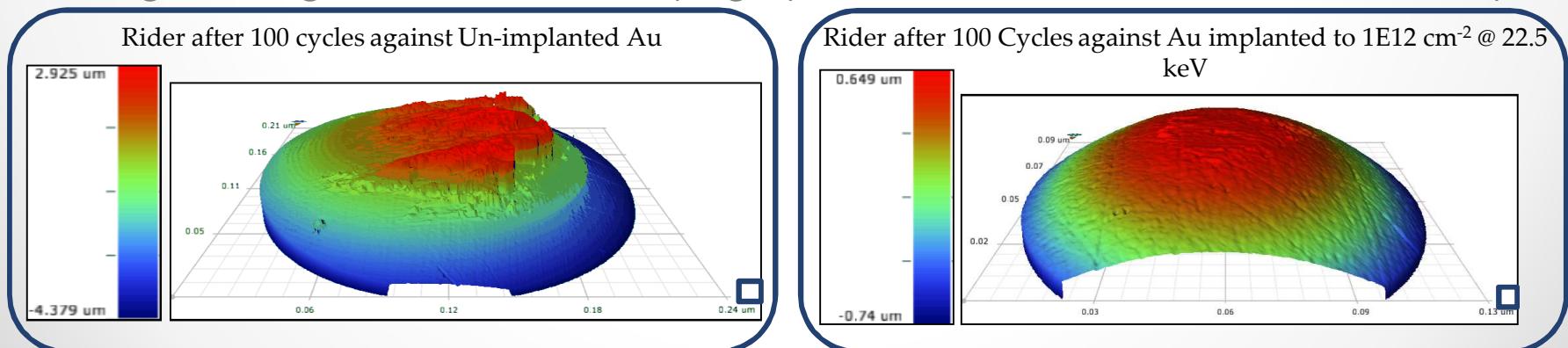


Factor of ~3  
Improvement  
in friction  
coefficient.



Minimal ECR  
change

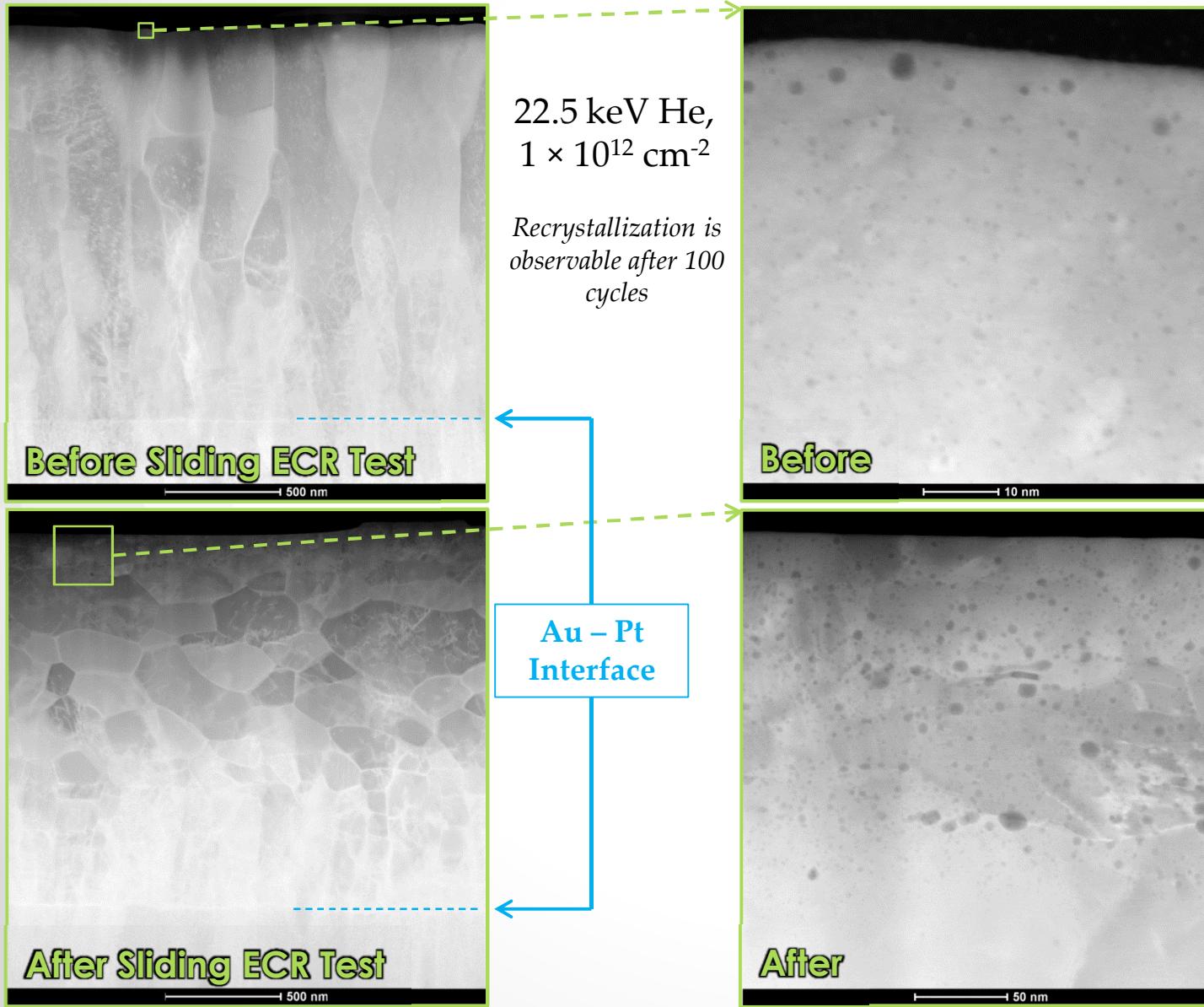
Friction significantly reduced with  $^3\text{He}$  implantation while maintaining ECR performance.  
Scanning white light interferometer topographical construction of riders after 100 cycles:



# STEM Images of Sub-surfaces



Collaborators: P. Kotula

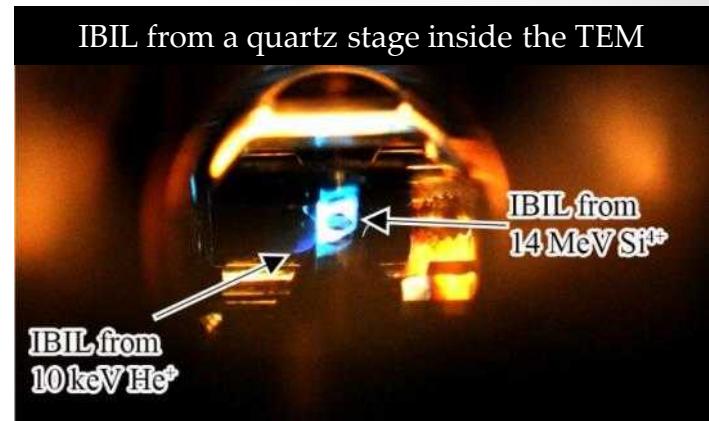
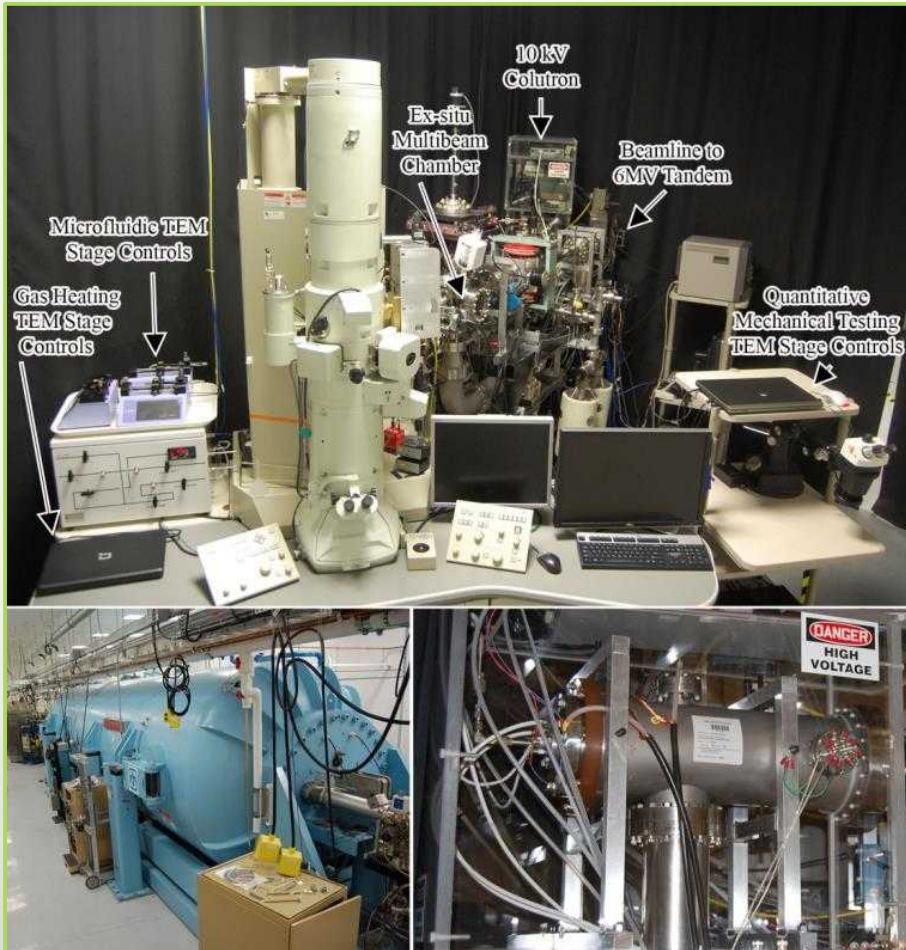


# Sandia's Concurrent *In situ* Ion Irradiation TEM



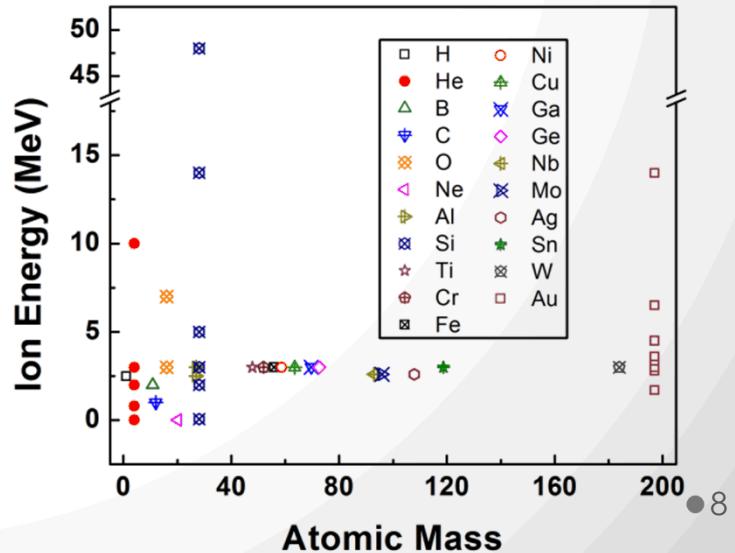
Collaborator: D.L. Boller

10 kV Colutron - 200 kV TEM - 6 MV Tandem



Direct real time observation of ion irradiation, ion implantation, or both with nanometer resolution.

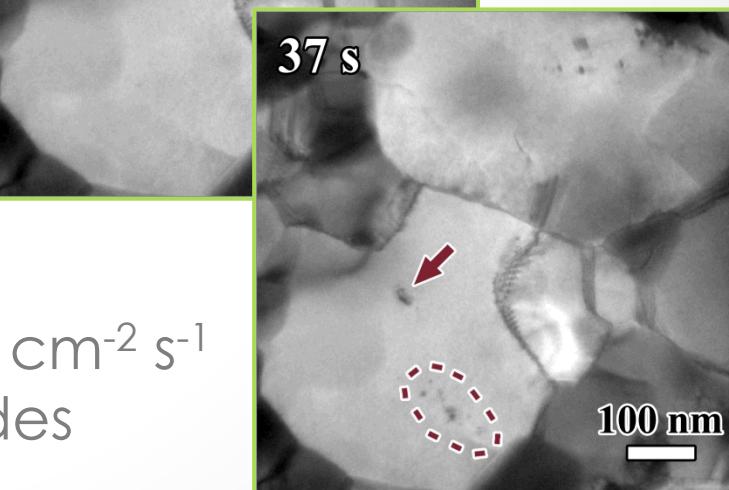
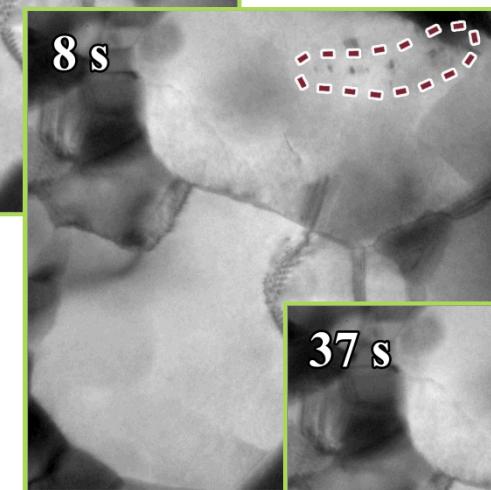
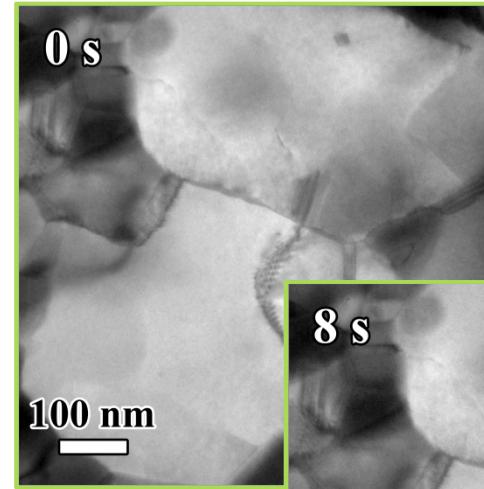
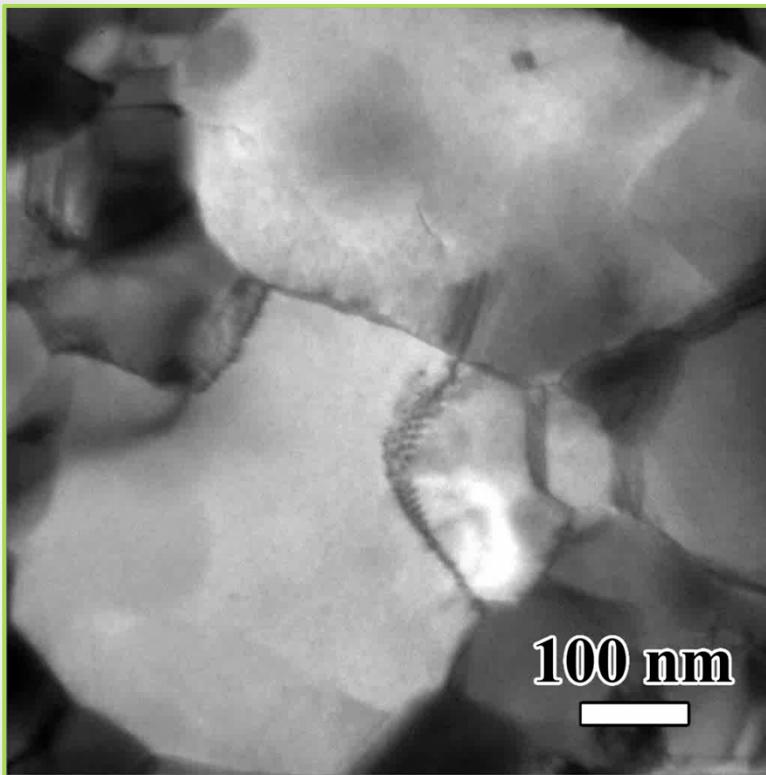
Ion species & energy introduced into the TEM



# TEM: 3.6 MeV Au<sup>6+</sup>

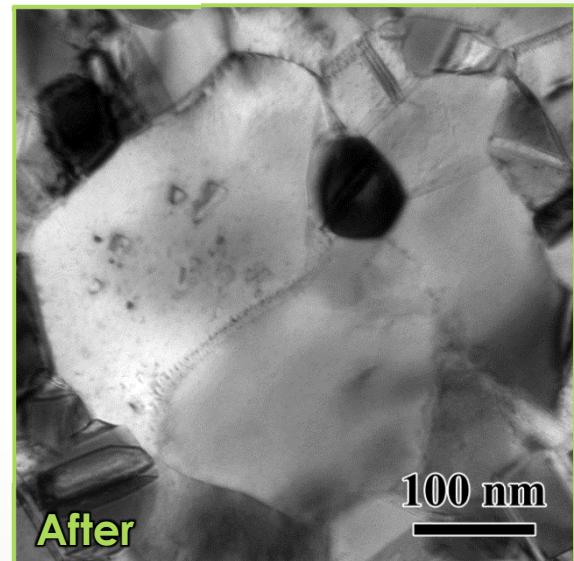
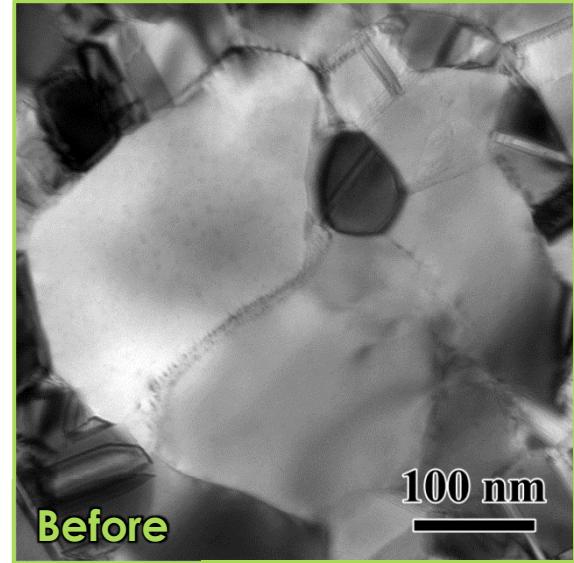


Video playback speed  $\times 5$ .



- 3.6 MeV Au<sup>6+</sup> ions at  $2.1 \times 10^8$  ions  $\text{cm}^{-2} \text{ s}^{-1}$
- Large defect clusters from cascades
- **Degradation of wear properties**

# TEM: 10 keV He<sup>+</sup>



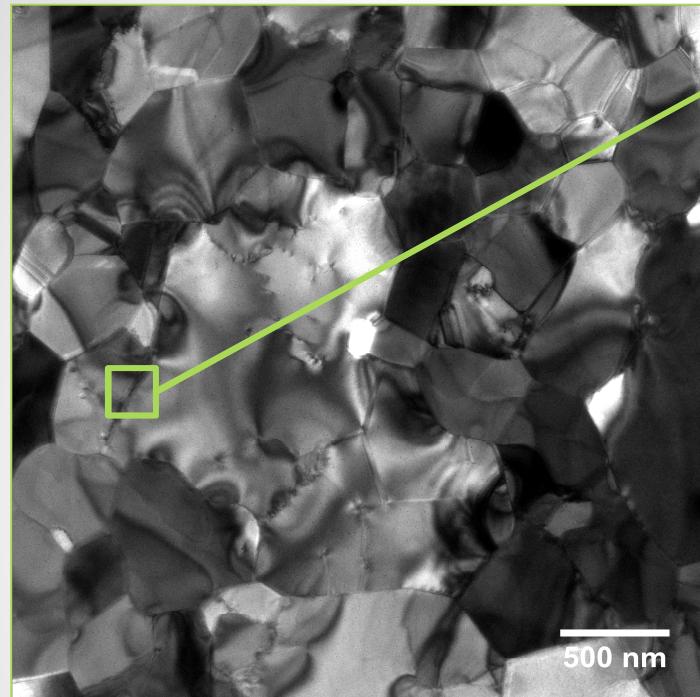
- 10 keV He<sup>+</sup> ions at  $2.9 \times 10^{13}$  ions cm<sup>-2</sup> s<sup>-1</sup>
- Gradual formation and growth of dislocation loops

● TMS 2015

# Extremes of *In Situ* Implantation

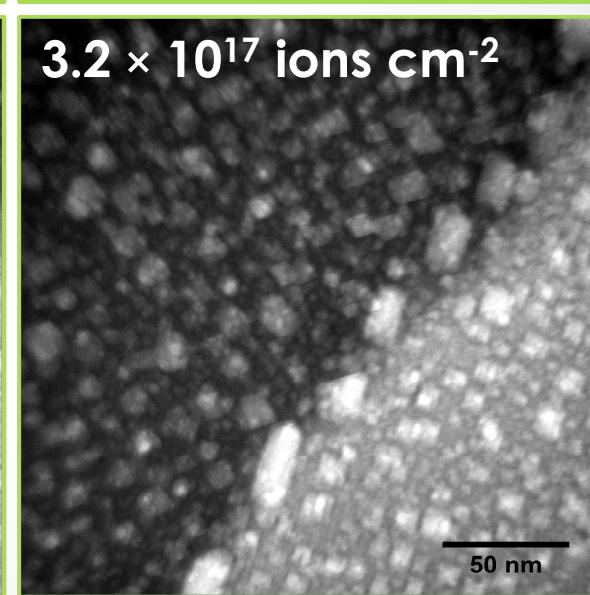
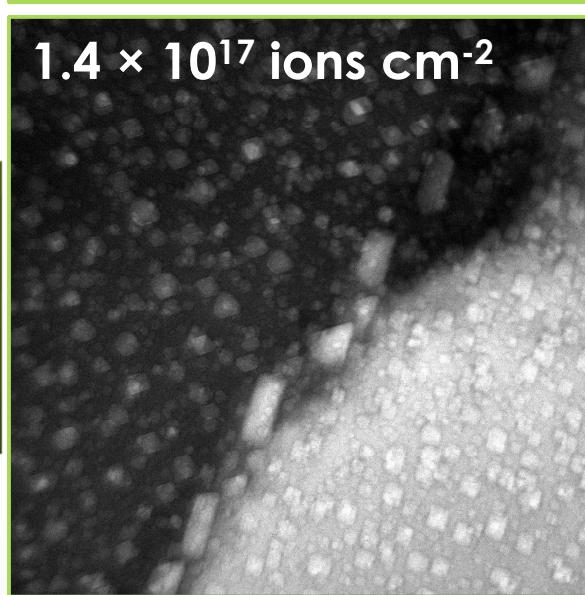
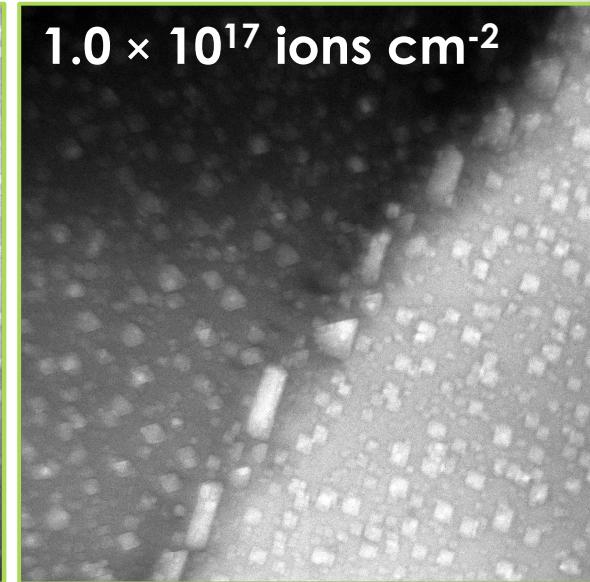
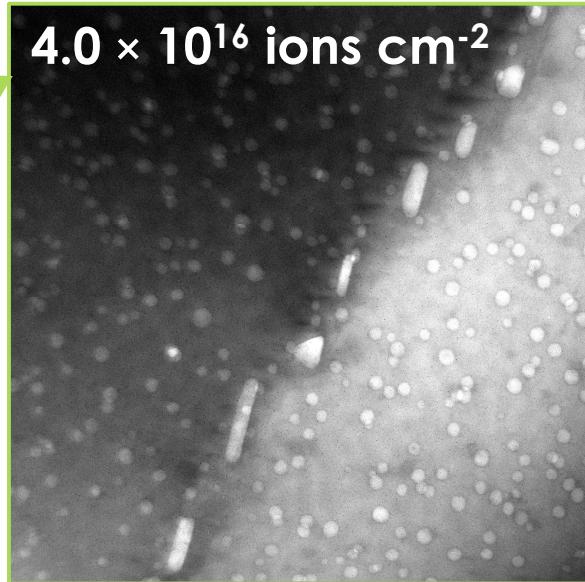


Collaborators: C. Chisholm, P. Hosemann, & A. Minor

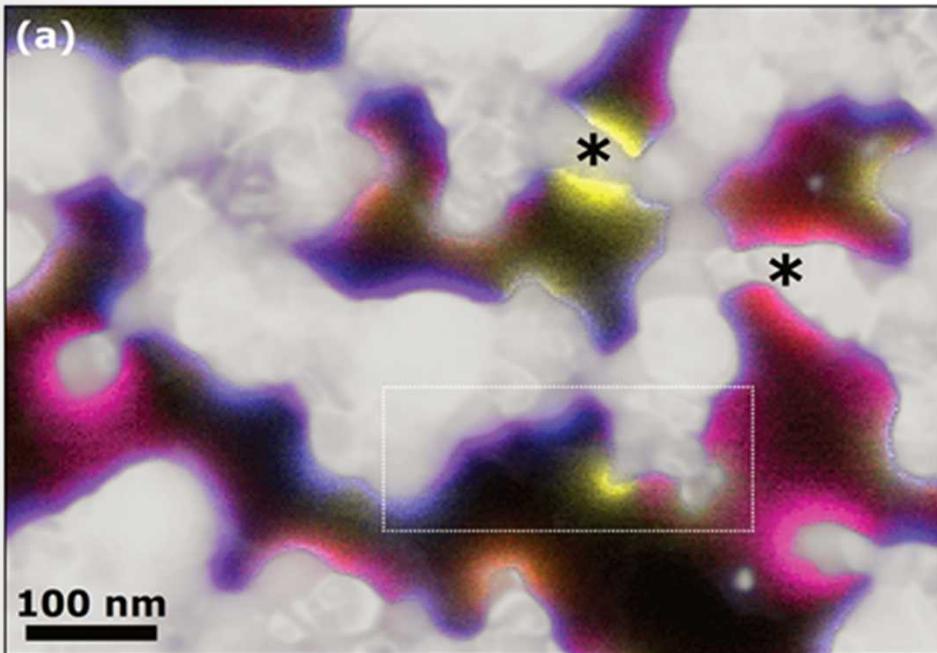


10 keV He<sup>+</sup> into Au TEM foil

Result: Faceted cavities form a porous microstructure.



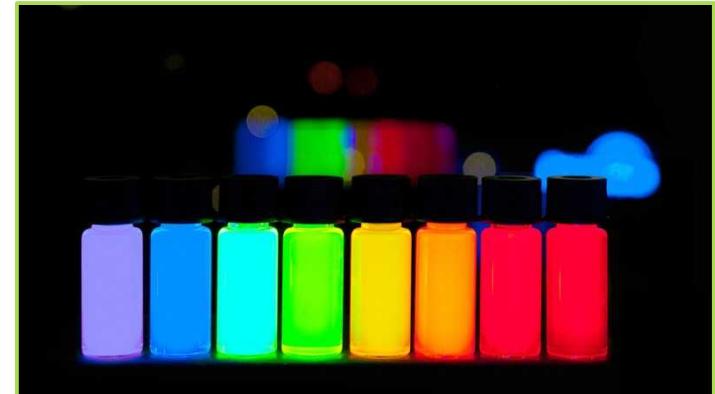
# Optical properties



Wavelength (nm)	1080	730	575	430	360
Energy (eV)	1.15	1.70	2.15	2.90	3.45

Bosman, *et al*, Nanotech, 2007.

Optical properties of nanostructured materials depend sensitively on size and shape.



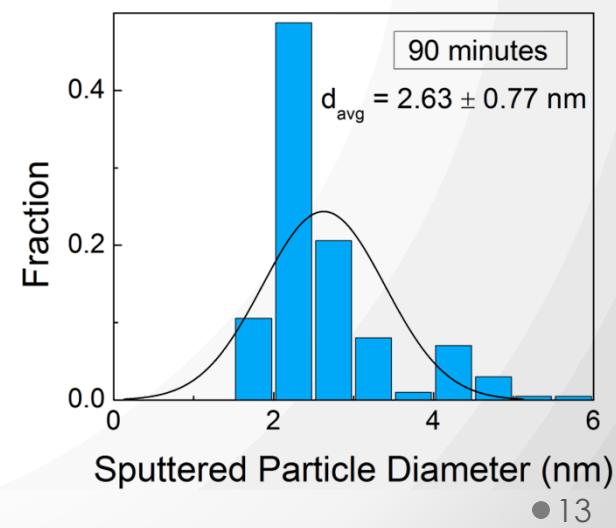
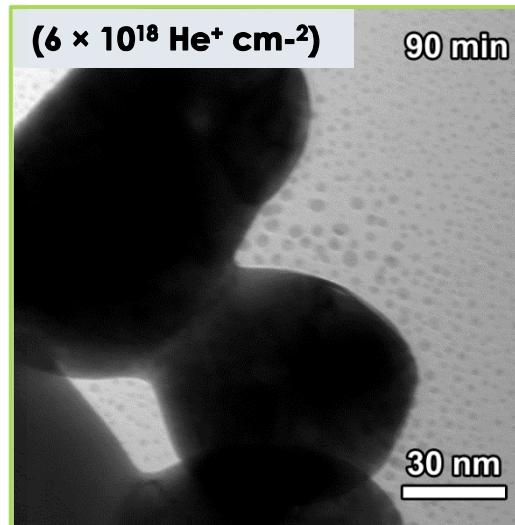
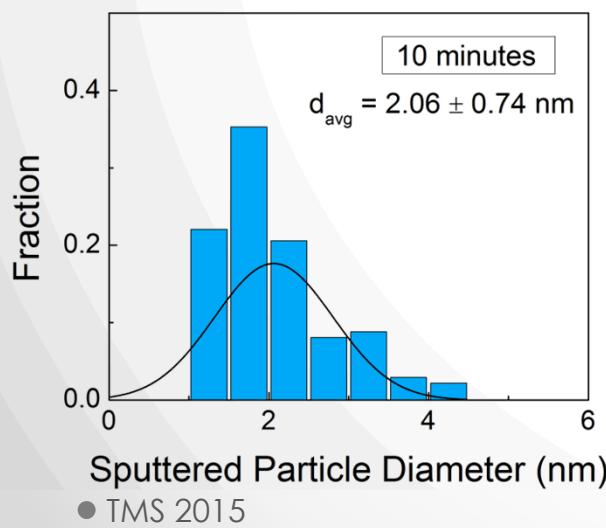
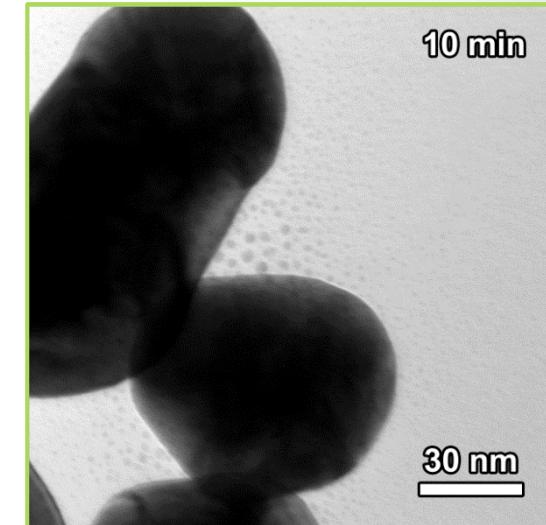
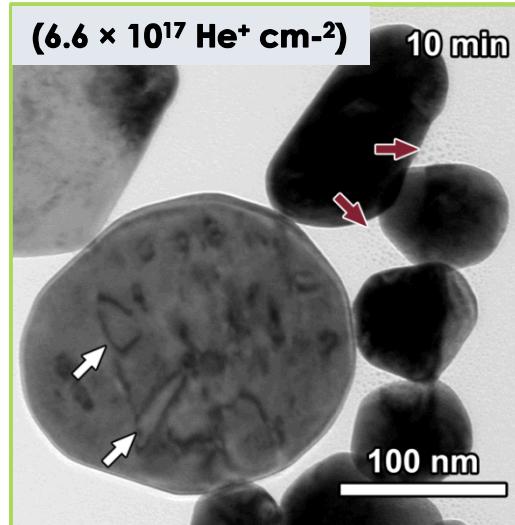
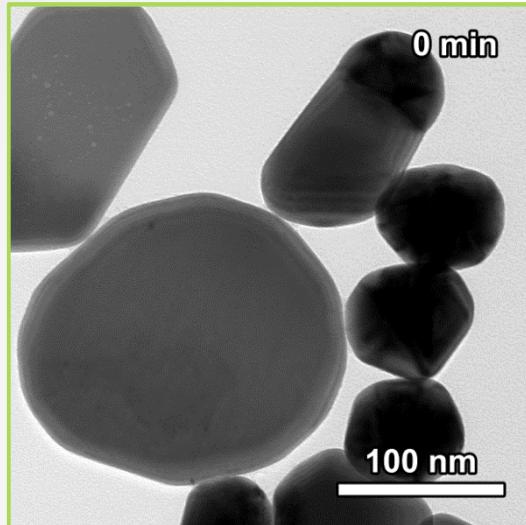
Antipoff, 2012, *via* Wikimedia Commons.

Ion beams can modify these materials in ways not possible by other means.

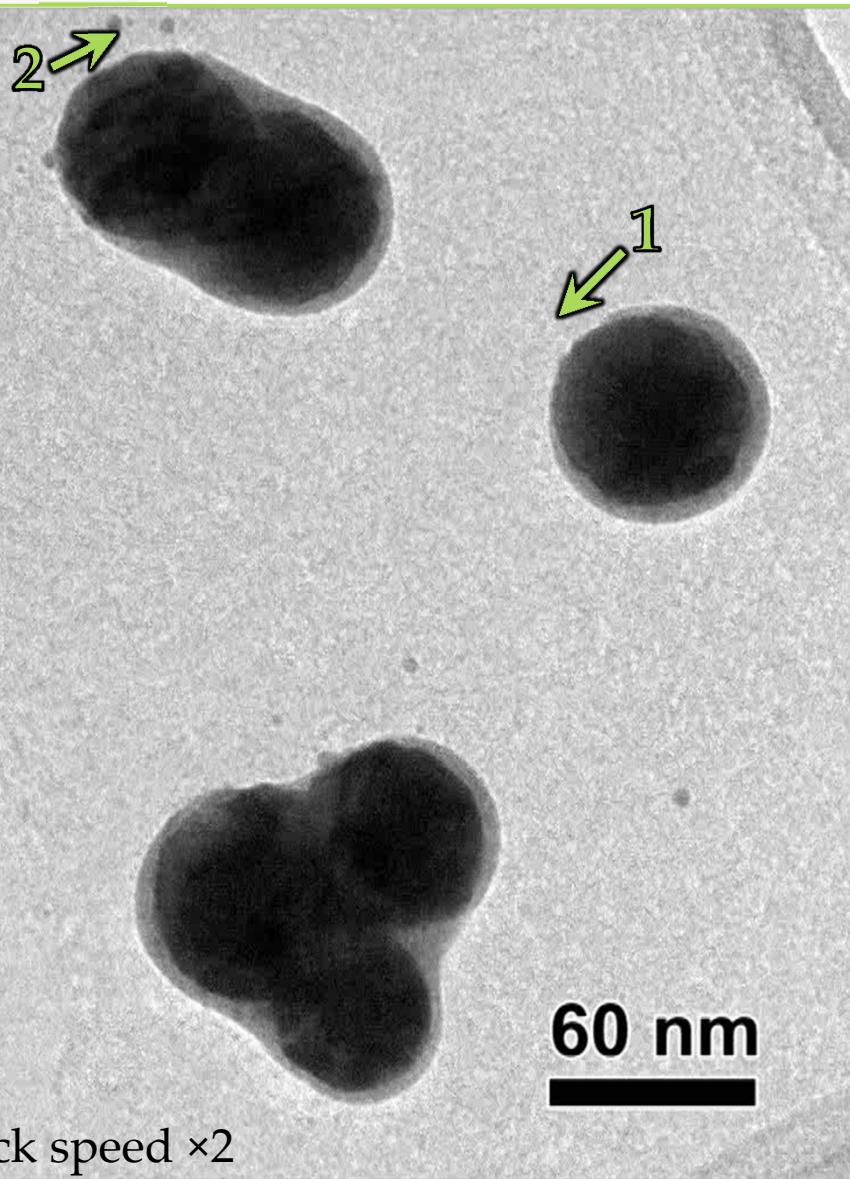
# Structural Modification of Nanoparticles by He implantation



Collaborators: S.H. Pratt & T.J. Boyle



# Single Ion Strikes



- 2.8 MeV  $\text{Au}^{4+}$  ions into 60 nm diameter Au nanoparticles
- 100 kx magnification
- Nanoscale filaments created by individual ions
  - Filaments evolve over time

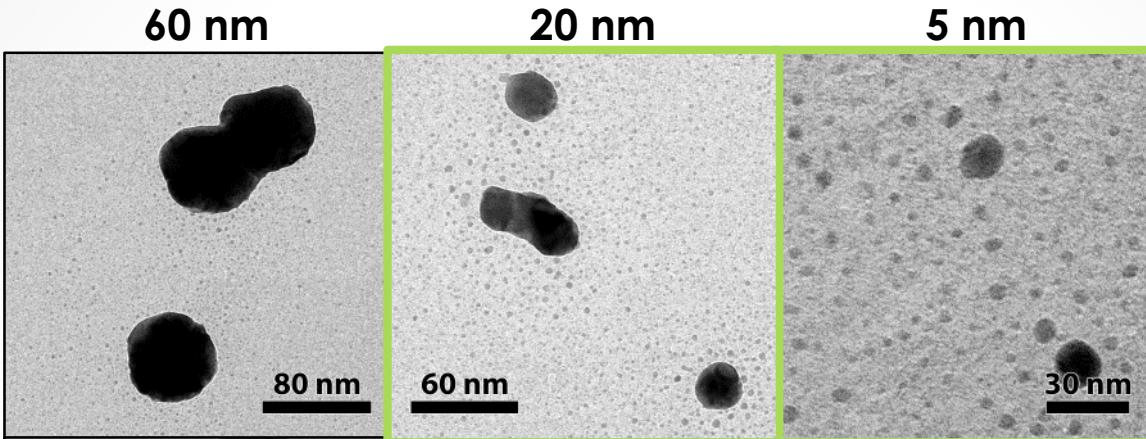
**The permanent and transient structures resulting from single ion strikes can be directly observed.**

Video playback speed ×2

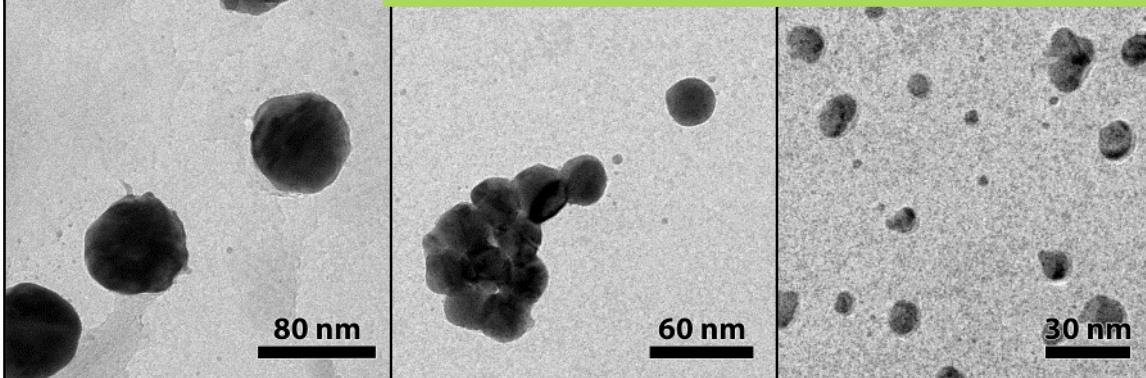
# Varying Ion Energy and Au Particle Size



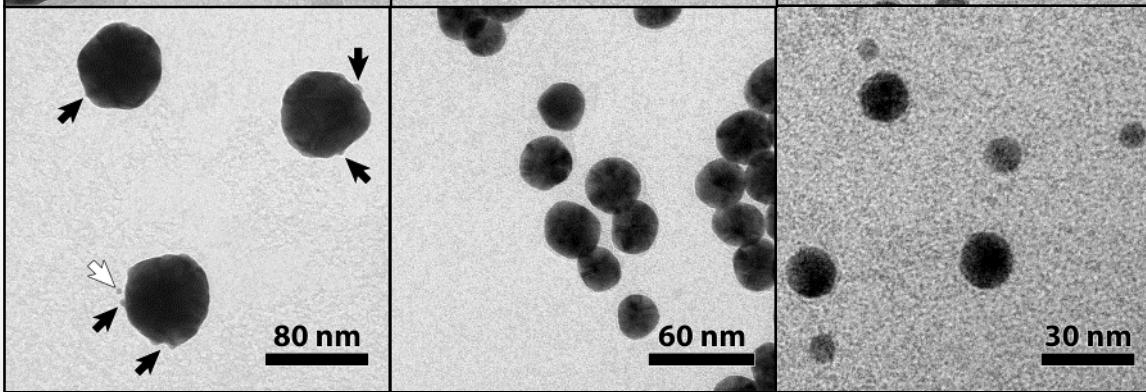
46 keV Au<sup>1-</sup>  
 $3.4 \times 10^{14} \text{ cm}^{-2}$



2.8 MeV Au<sup>4+</sup>  
 $4 \times 10^{13} \text{ cm}^{-2}$



10 MeV Au<sup>8+</sup>  
 $1.3 \times 10^{12} \text{ cm}^{-2}$

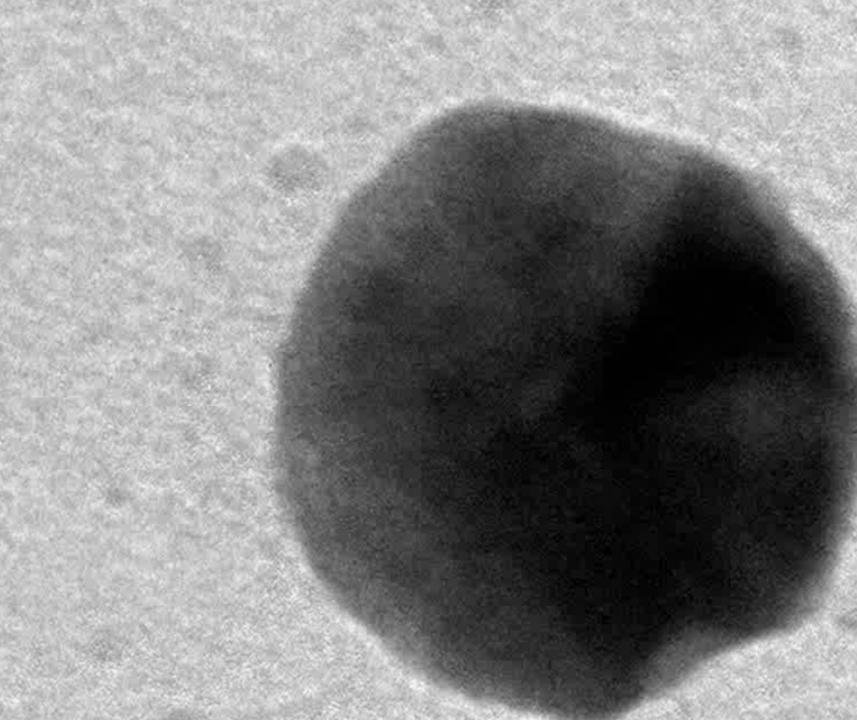


Particle size and ion energy dictate the ratio of sputtering, particle motion, particle agglomeration, and other active mechanisms.

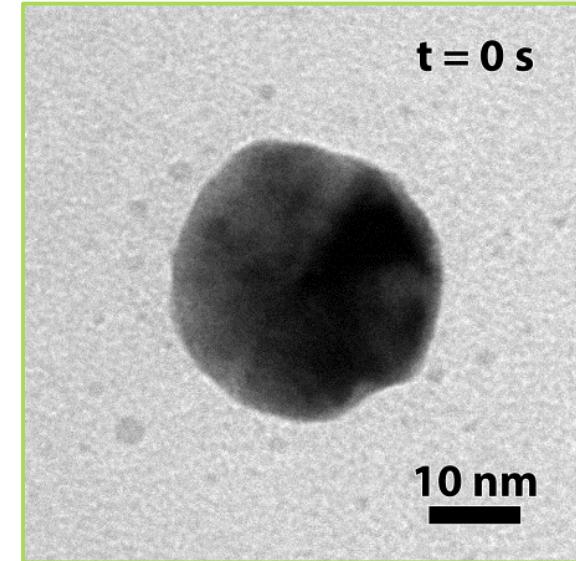
# Single Ion Effects: 20 nm



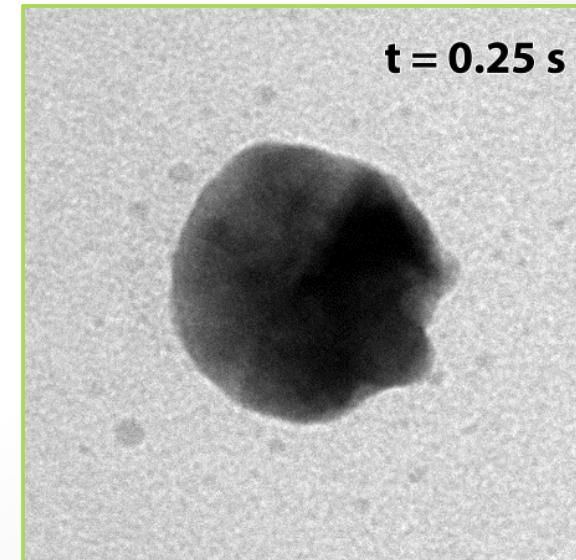
**46 keV Au<sup>1-</sup> ions**



**10 nm**



**10 nm**



# Single Ion Effects: 5 nm



**46 keV Au<sup>1+</sup> ions**

**10 nm**  
—

**t = 0 s**

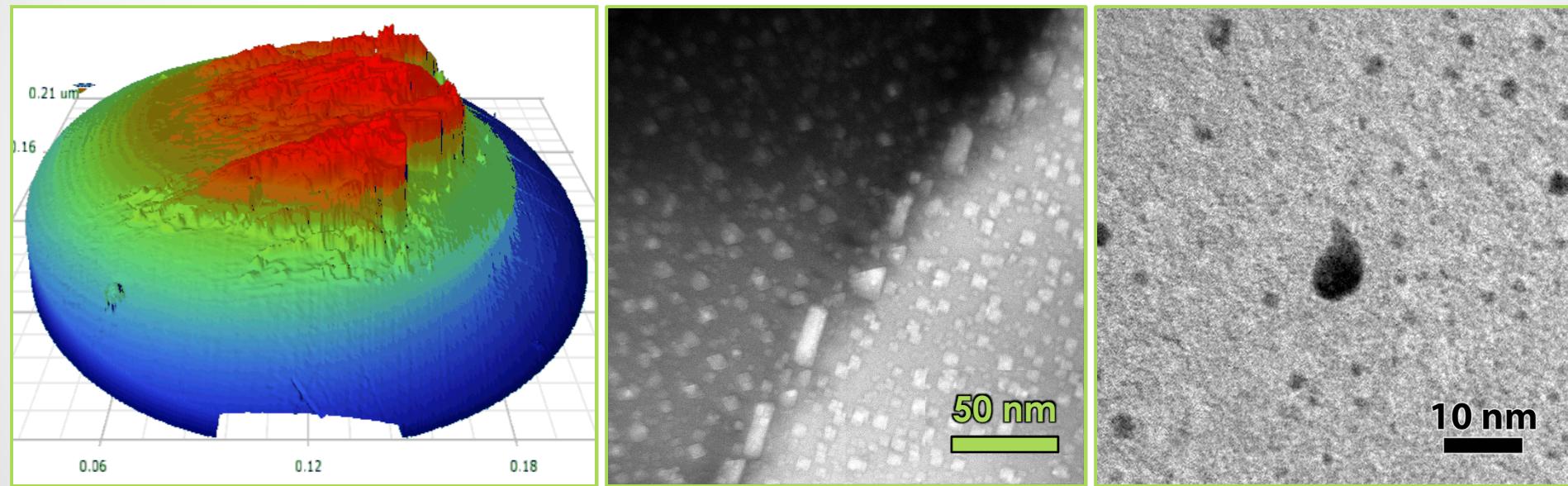
**10 nm**  
—



# Summary and Conclusions



- Demonstrated improvement in Au sliding contacts via He implantation
- Ion beams may also be used to change shape and size of nanoparticles



- Acknowledgements: Prof. T.W. Scharf (UNT), P. Hosemann (UC Berkeley), C. Chisholm & A. Minor (UC Berkeley and LBNL), T.J. Boyle, D.L. Buller, P. Kotula, S.H. Pratt. This work was partially supported by the Division of Materials Science and Engineering, Office of Basic Energy Sciences, U.S. Department of Energy.